IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

n re Application of:	
:	Examiner: J. G. Jelsma
Takako YAMAGUCHI et al.)	
;	Group Art Unit: 1795
Application No.: 10/529,891)	
	Confirmation No.: 7802
Completion of Entry into U.S. National	
Stage Under 35 U.S.C. § 371(c): July 26, 2005	
)	
For: EXPOSURE MASK, METHOD OF DESIGNING:	
AND MANUFACTURING THE SAME,)	
EXPOSURE METHOD AND APPARATUS, :	
PATTERN FORMING METHOD, AND DEVICE)	
MANUFACTURING METHOD :	November 3, 2009

Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated August 3, 2009, please amend the aboveidentified application as follows: